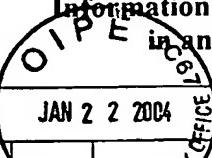


PTO-1449 Information Disclosure Citation in an Application		Application No. 10/607,944	Applicant(s) Pascal Huyghe et al.			
		Docket Number 064441.0263	Group Art Unit 2122	Filing Date June 27, 2003		
JAN 22 2004 		U.S. PATENT DOCUMENTS				
PATENT & TRADEMARK OFFICE	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A. MA	5909570	6/1/99	Webber	395	500	6/9/97
B. MA	6012070	1/4/00	Cheng et al.	707	505	11/15/96
C. MA	2002/0184266	12/5/02	Blessin	707	513	3/20/02
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FOREIGN PATENT DOCUMENTS						
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
L. MA	01/63446 A2 ✓	8/30/01	WO	G06F	17/00	X
M. MA	02/03141 A2 ✓	1/10/02	WO	G03F	1/00	X
N.						
O.						
P.						
Q.						
NON-PATENT DOCUMENTS						
	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)					DATE
R.	PCT International Search Report application number PCT/US03/20345, 7 pages.					Mailing 12/19/03
S.						
T.						
EXAMINER <i>Hayraph</i>			DATE CONSIDERED 8/31/2006			
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PTO-1449 Information Disclosure Citation in an Application	Application No.	Applicant(s)	
	Unassigned	Pascal Huyghe et al.	
	Docket Number 064441.0263	Group Art Unit Unknown	Filing Date June 27, 2003

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K.						

FOREIGN PATENT DOCUMENTS

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MA R.	Edward Suttle et al.'s "Streamlining the front-end reticle fabrication process by improving mask ordering" at internet address < http://www.micromagazine.com/archive/02/06/suttle.html > and published in June 2002 Issue of Micro Magazine. 10 Pages	June 2002
MA S.	Brock Hotaling, "MaskPilot Revolutionizes Semiconductor Software," <u>Reticle and Mask Solutions</u> , Vol. I, No. 1, Fall 2002, 4 Pages	Fall 2002
MA T.	Photronics, Inc., "Photronics eBeam Phase Masks: Tackling the Challenges of Special Lightwave Applications," <u>Reticle and Mask Solutions</u> , Vol. XIII, No. 1, Spring 2002, 4 Pages	Spring 2002

EXAMINER	DATE CONSIDERED
<i>Huyghe</i>	8/3/2006

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.